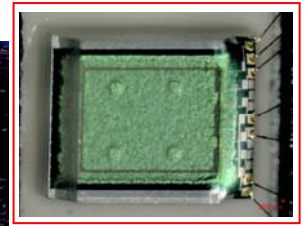
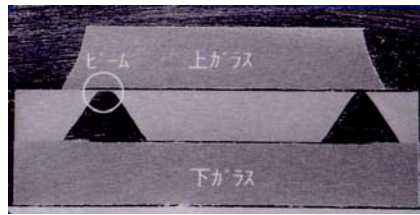
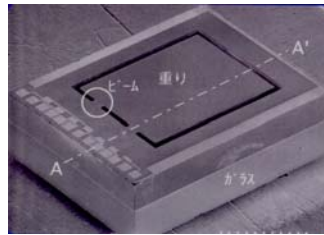
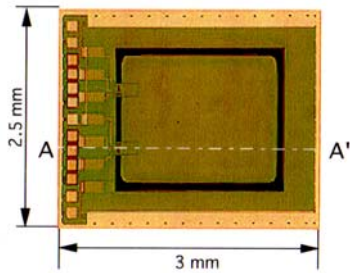
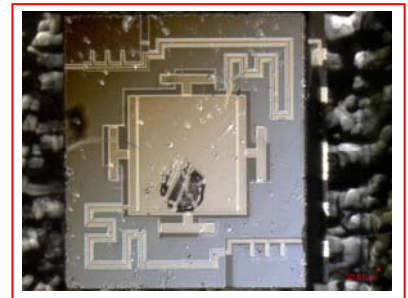
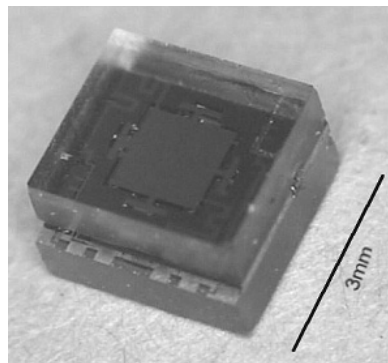
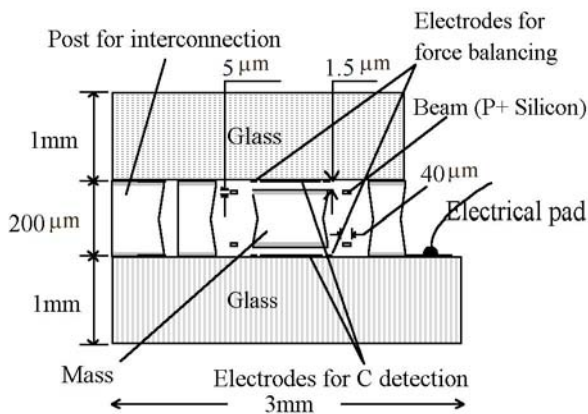


Various Accelerometers



Piezoresistive accelerometer (Panasonic Electric Works)

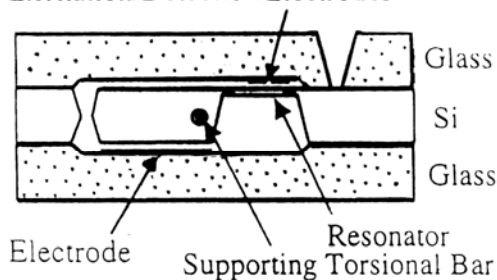
Reference : High-accuracy high-reliability MEMS accelerometer, Technical Report of Panasonic Electric Works (Nov.2003) pp.15-21



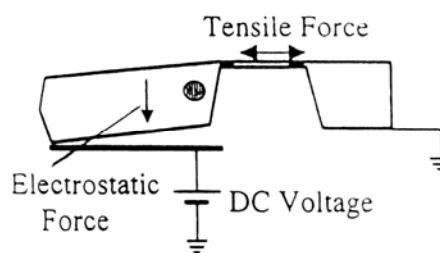
Narrow gap capacitive servo accelerometer (Tohoku Univ. – Samsung)

Reference : G.Lim, S.Baek and M.Esashi : A New Bulk-Micromachining Using Deep RIE and Wet Etching for an Accelerometer, Trans. IEE of Japan, 118-E (1998) pp.420-424

Excitation/Detection Electrodes

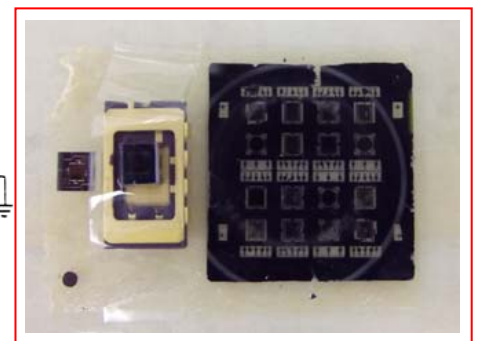


(a) Structure

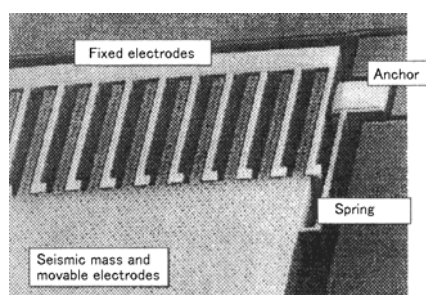
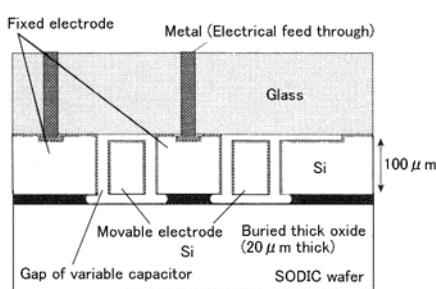


(b) Working Principle

Resonating accelerometer



Reference : H.Hashimoto, K.Minami and M.Esashi, Silicon Resonant Accelerometer, Technical Digest of the 13th Sensor Symposium (1995) pp.181-184



Capacitive accelerometer using deep RIE of SOI wafer with thick buried oxide (Tohoku Univ. – Daimler-Chrysler)